



US00D944661S

(12) **United States Design Patent** (10) **Patent No.:** **US D944,661 S**  
**Sambu et al.** (45) **Date of Patent:** **\*\* Mar. 1, 2022**

(54) **CALIBRATOR FOR WAFER HANDLING  
ROBOTS**

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(\*\*) Term: **15 Years**

(21) Appl. No.: **29/716,452**

(22) Filed: **Dec. 10, 2019**

(30) **Foreign Application Priority Data**

Jul. 17, 2019 (JP) ..... 2019-015964

(51) **LOC (13) Cl.** ..... **10-04**

(52) **U.S. Cl.**  
USPC ..... **D10/49; D13/182**

(58) **Field of Classification Search**  
USPC ..... D10/46, 47, 49, 61–62, 64–66, 70–78,  
D10/80, 81, 83, 84, 85, 103; D13/182;  
D15/140, 144.1  
CPC ..... H01L 21/67742; G05B 2219/45031; B25J  
9/1692  
See application file for complete search history.

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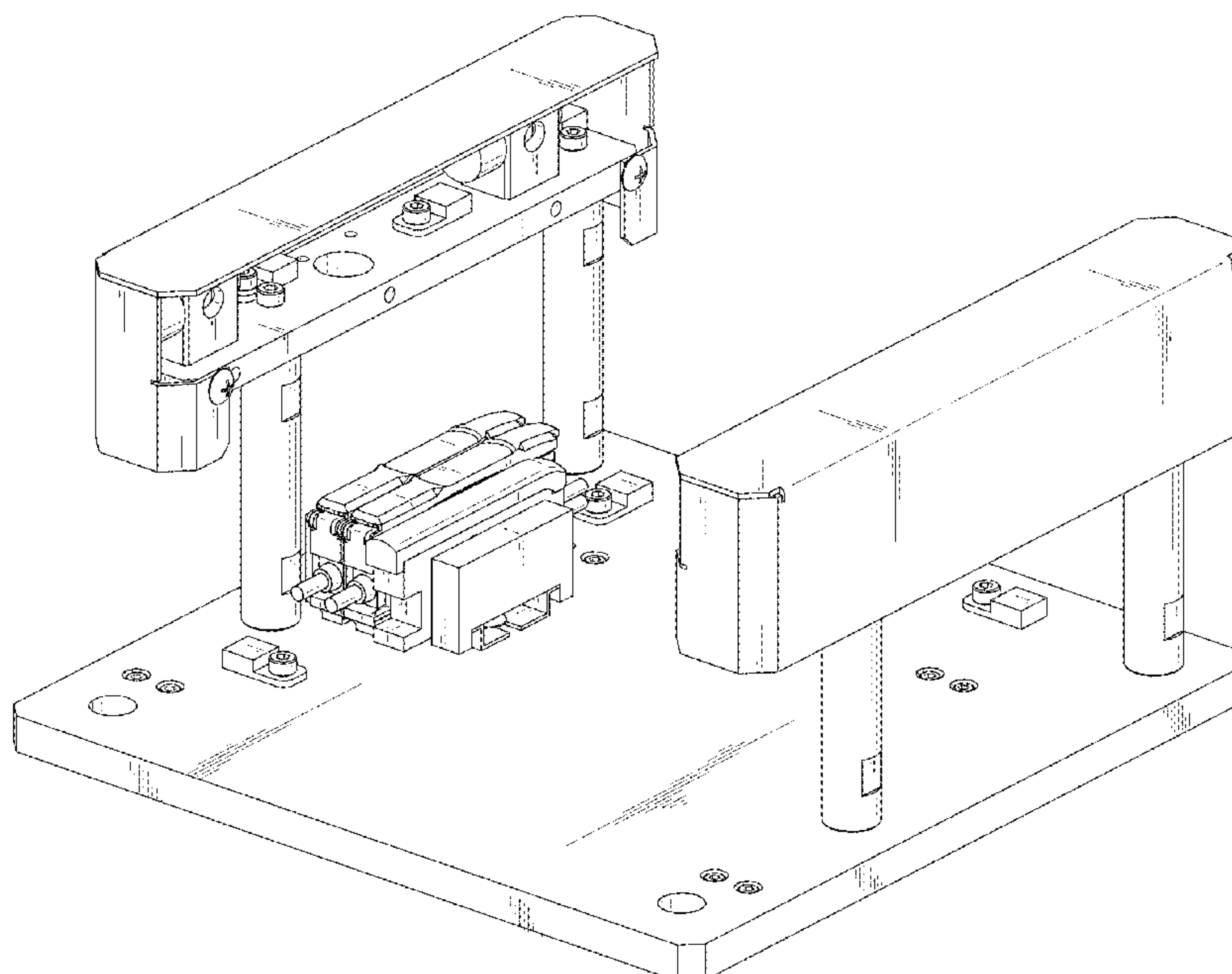
(57) **CLAIM**

We claim the ornamental design for a calibrator for wafer  
handling robots, as shown and described.

**DESCRIPTION**

FIG. 1 is a front, top and right side perspective view of a  
calibrator for wafer handling robots showing our new  
design;  
FIG. 2 is a front elevational view thereof;  
FIG. 3 is a rear elevational view thereof;  
FIG. 4 is a right side elevational view thereof;  
FIG. 5 is a left side elevational view thereof;  
FIG. 6 is a top plan view thereof;  
FIG. 7 is a bottom plan view thereof;  
FIG. 8 is a cross-sectional view take along line 8-8 in FIG.  
2; and,  
FIG. 9 is a cross-sectional view take along line 9-9 in FIG.  
2.

**1 Claim, 9 Drawing Sheets**



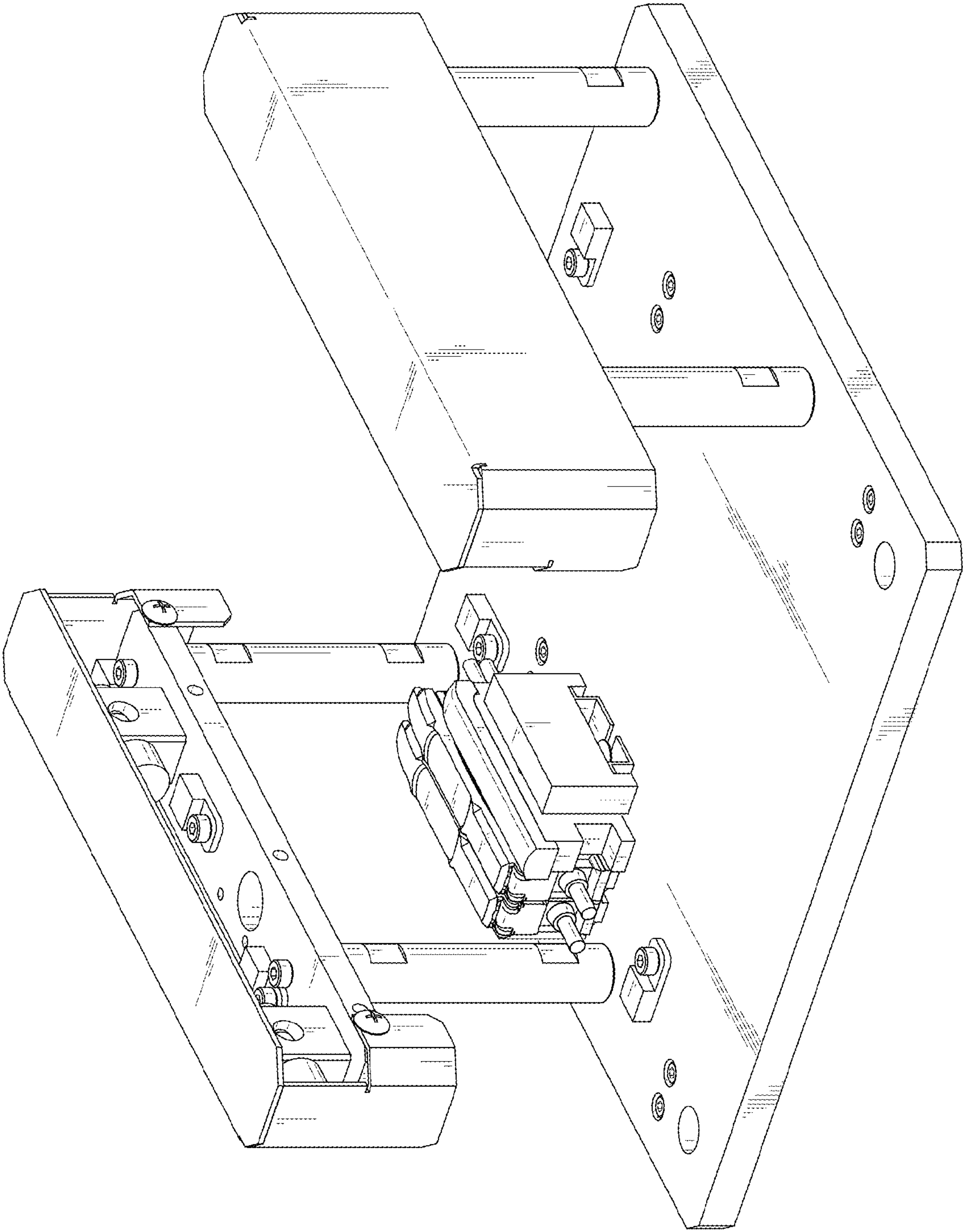
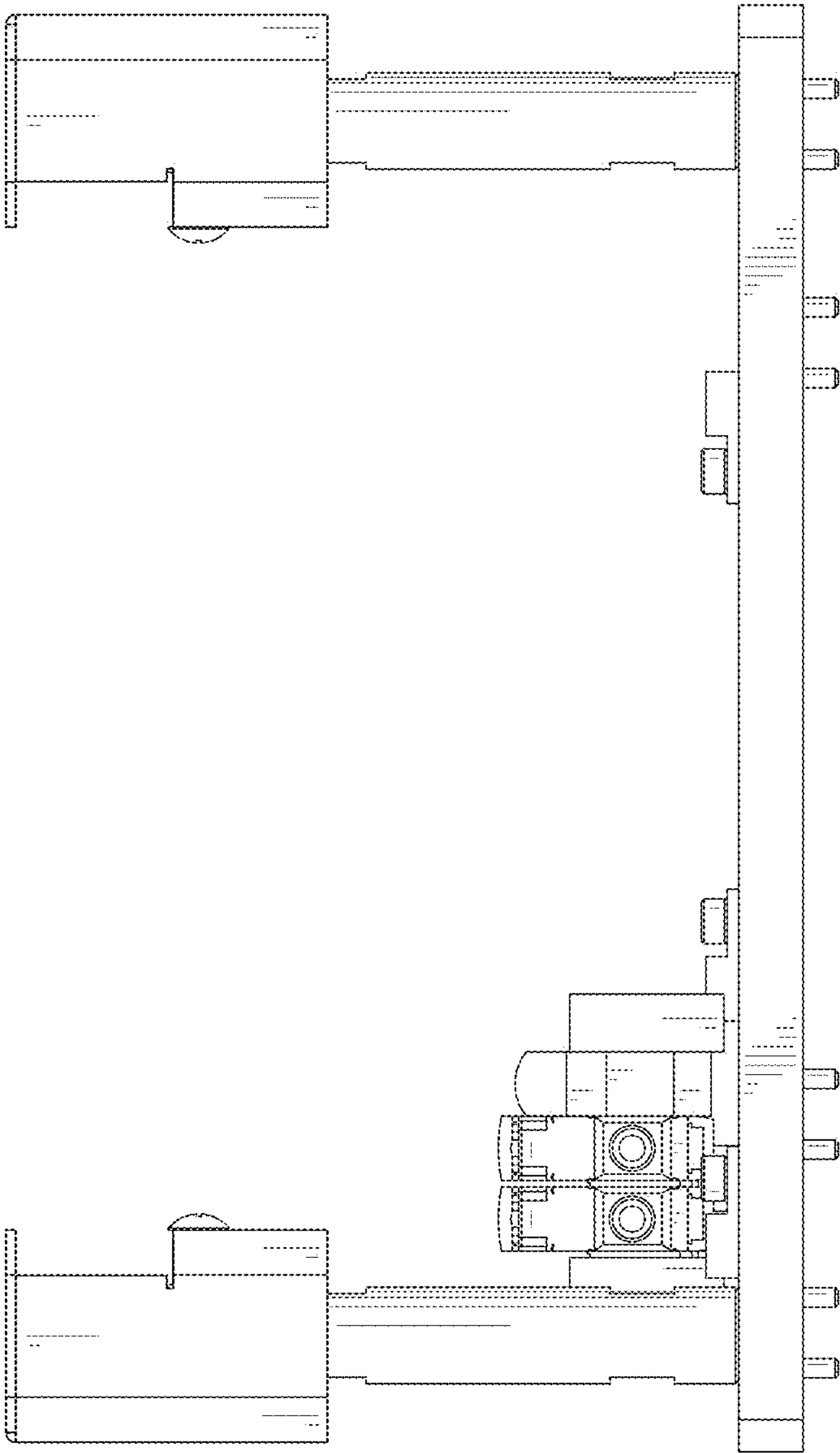


FIG. 1

8 9



8 9

FIG. 2

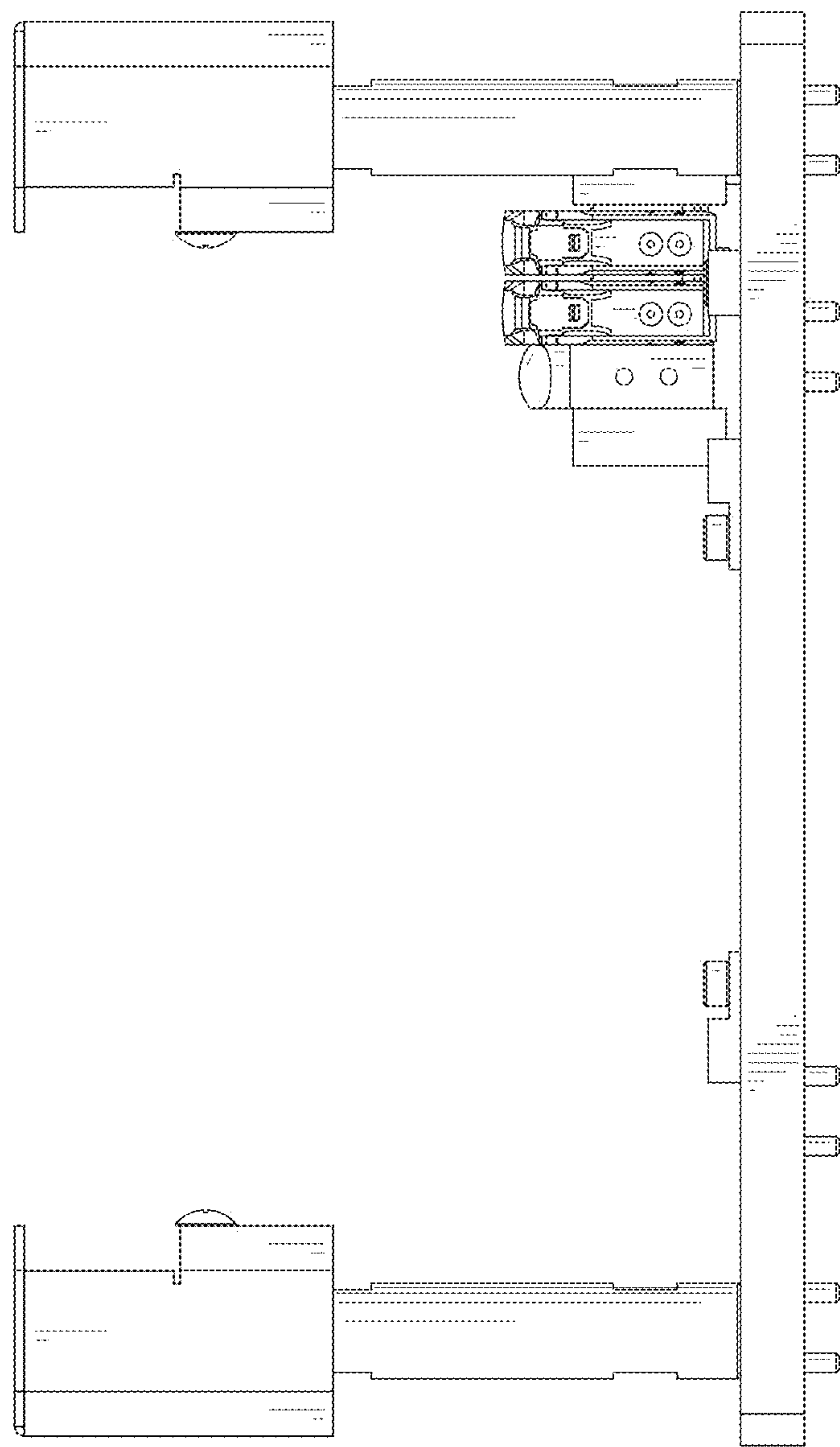


FIG. 3

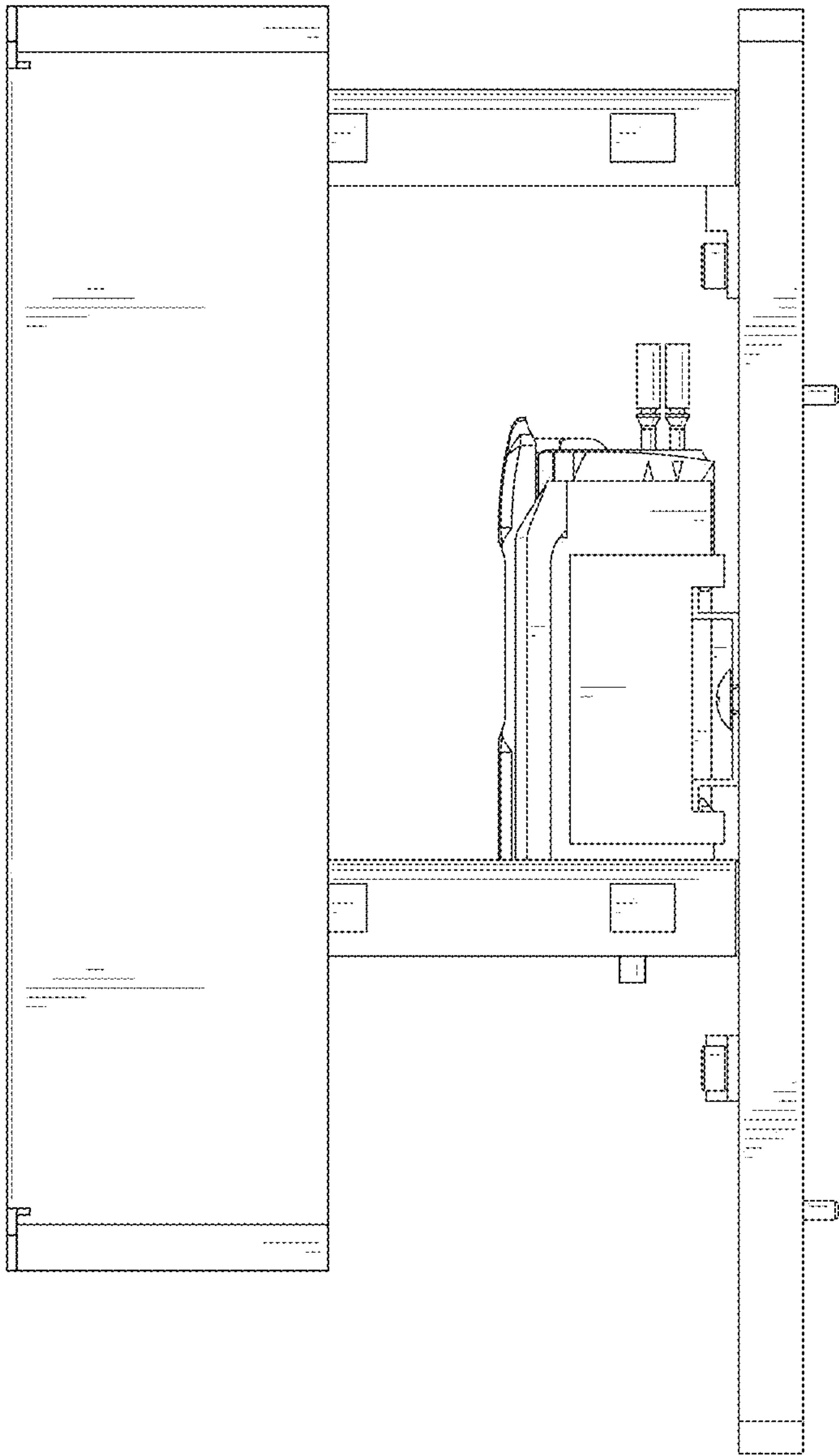


FIG. 4

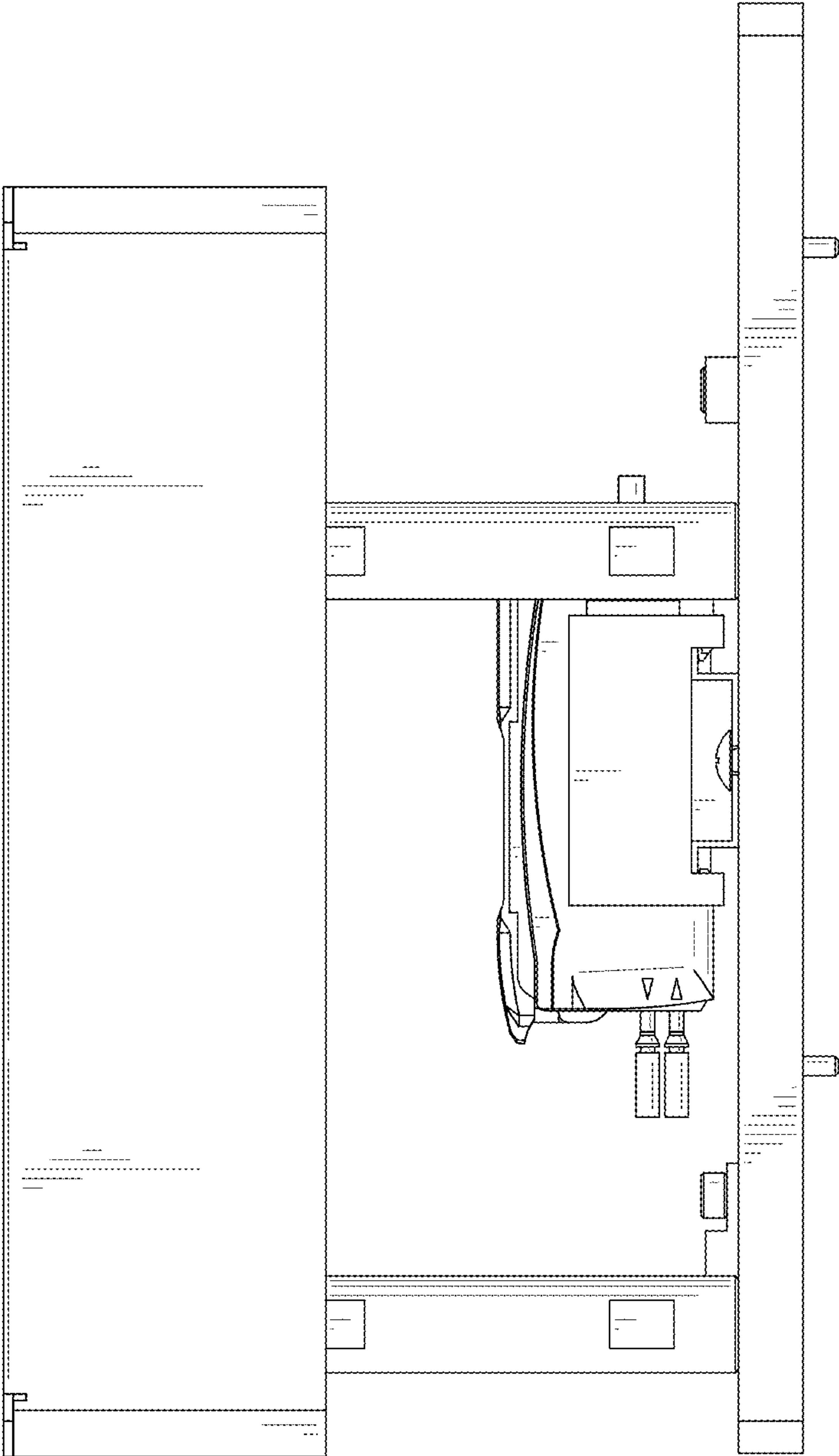


FIG. 5

FIG. 6

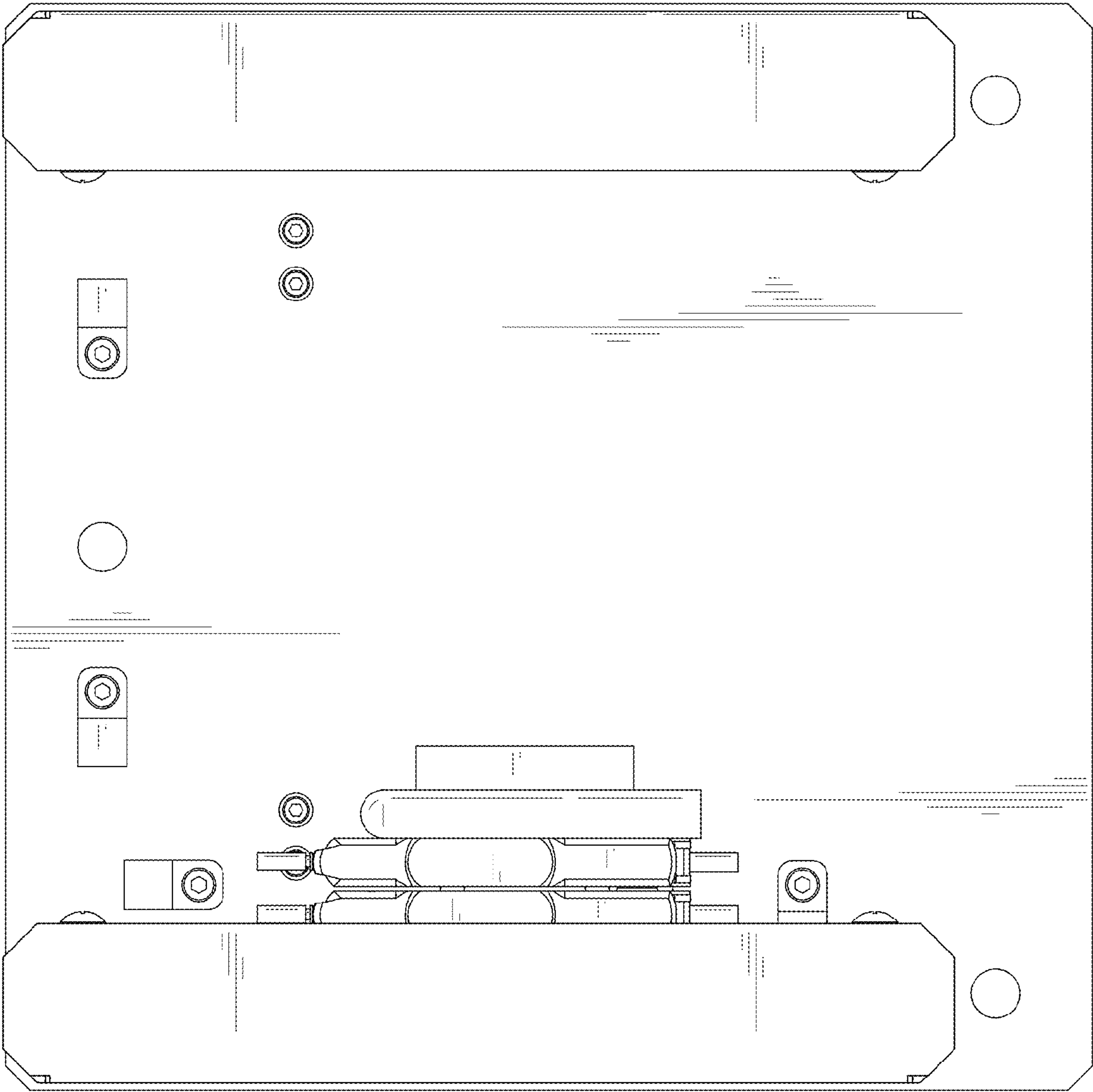
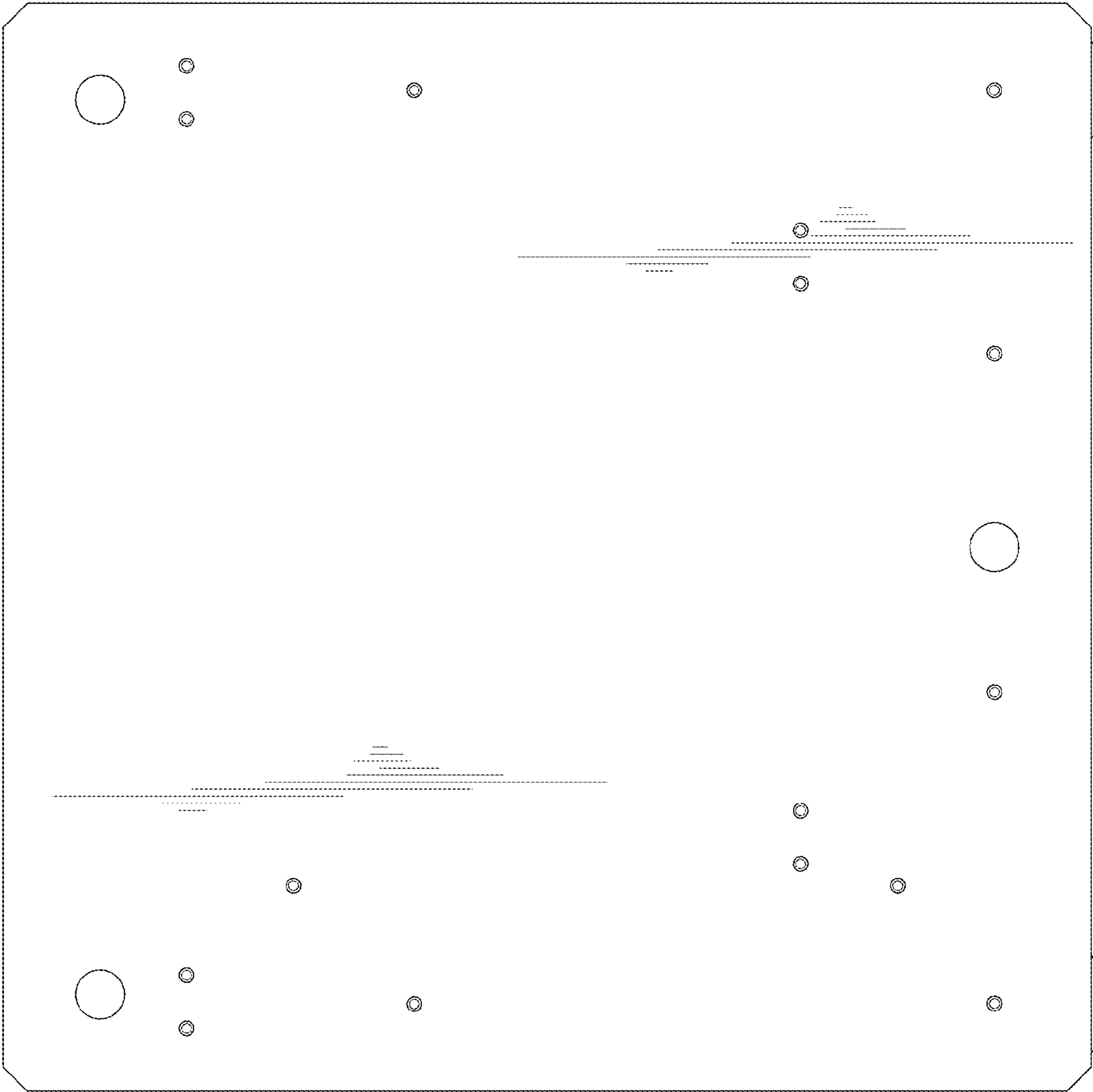


FIG. 7



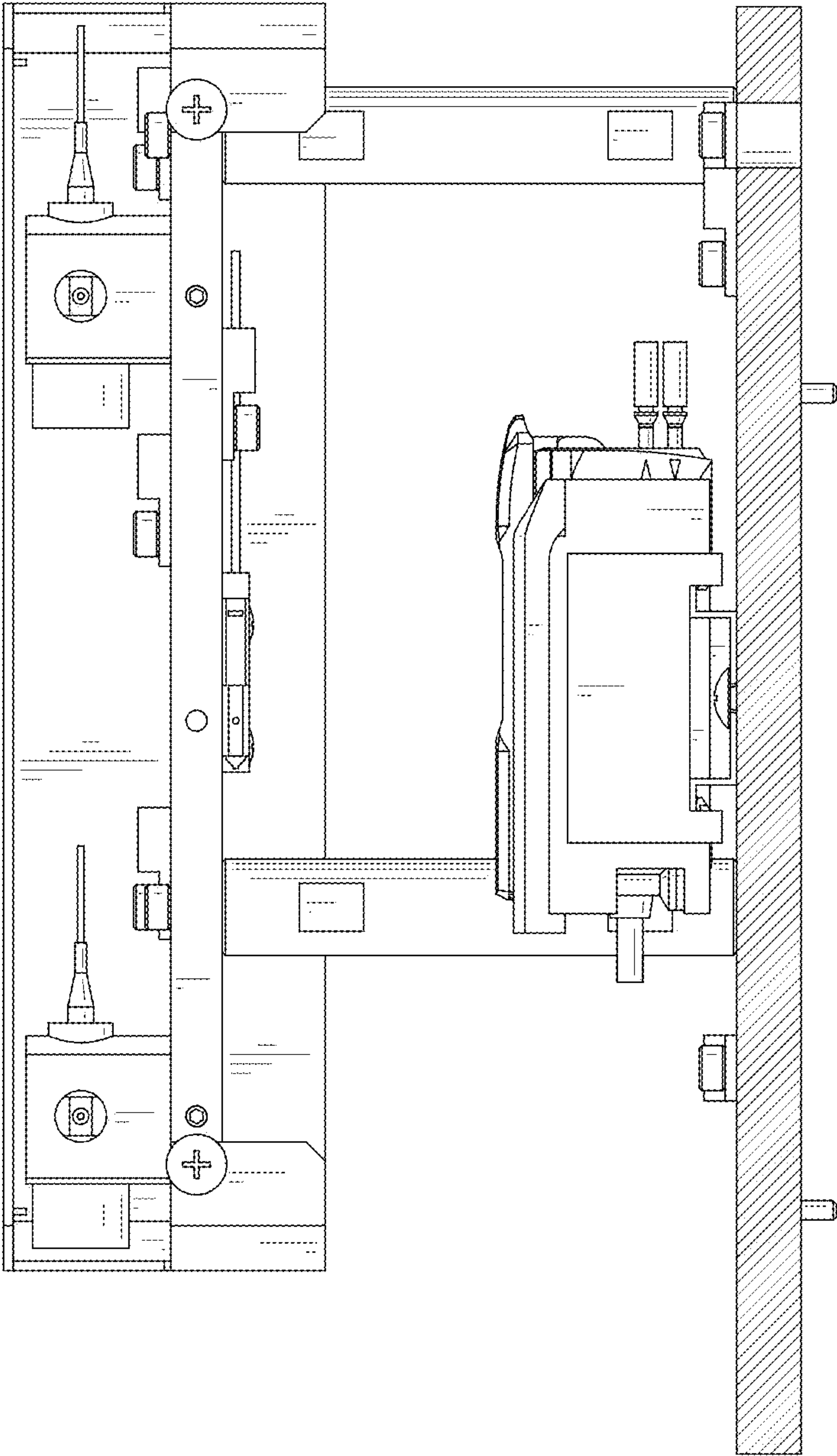


FIG. 8

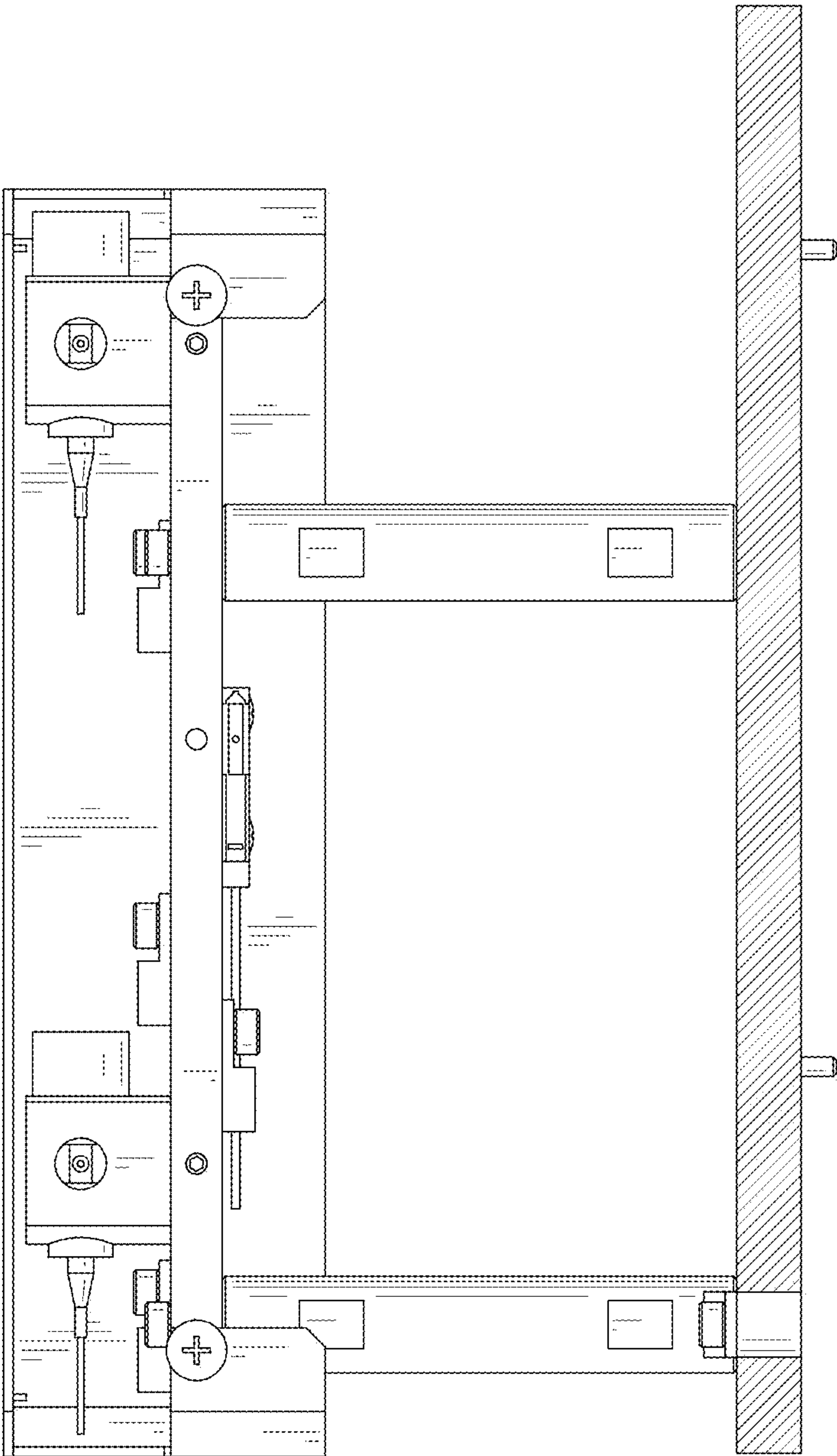


FIG. 9